AMENDMENTS TO THE CLAIMS

Please amend claims 6, 18, 21 and 25, and cancel claim 13, such that the status of the claims is as follows:

1-5. (Canceled)

6. (Currently Amended) A device for moistening a cleanroom material to a target saturation level, the device comprising:

a chamber;

a rack positioned in the chamber for holding the cleanroom material;

a liquid supply of a liquid;

an applicator in the chamber for applying the liquid to the cleanroom material;

a delivery system for delivering the liquid from the supply to the applicator;[[and]]

a user interface for inputting the target saturation level of the cleanroom material; and

a control system for controlling the amount of liquid applied to the cleanroom material ~~based on~~ as a function of a parameter related to the target saturation level of the cleanroom material.

7. (Previously Presented) The device of claim 6 wherein the control system controls the amount of liquid dispensed to the cleanroom material as a function of electrical conductivity of the cleanroom material.

8. (Previously Presented The device of claim 6 wherein the control system controls the amount of liquid dispensed to the cleanroom material as a function in mass of the cleanroom material.

9. (Previously Presented) The device of claim 6 wherein the control system controls the amount of liquid dispensed to the cleanroom material as a function of a time duration.

10. (Original) The device of claim 6 wherein the rack is centrally positioned within the chamber.

11. (Original) The device of claim 6 wherein the applicator includes a pump for pumping the liquid under pressure and a nozzle for applying the liquid.

12. (Previously Presented) The device of claim 6 wherein the control system includes a pump control for controlling the amount of liquid applied to the cleanroom material.

13. (Canceled)

14. (Original) The device of claim 6 wherein the control system includes a feedback sensor for providing a feedback signal representing the parameter.

15. (Previously Presented) The device of claim 6 wherein the control system includes a shut off sensor for providing a signal to the control system to disengage from the application of liquid to the cleanroom material when the chamber is in an open position.

16. (Original) The device of claim 6 wherein the chamber has a drain for draining excess liquid.

17. (Original) The device of claim 16 wherein the drain leads to a liquid collection system.

18. (Currently Amended) A device for moistening a cleanroom material, the device comprising:

a rack for holding the cleanroom material;

an applicator spaced from and directed toward the rack for applying a liquid to the cleanroom material;[[and]]

a user interface for entering a desired saturation level of the cleanroom material; and

a control system for controlling application of liquid to the cleanroom material ~~based~~

~~on a~~ as a function of the desired saturation level of the cleanroom material and a sensed parameter related to an actual saturation level of the cleanroom material.

19. (Original) The device of claim 18 wherein the applicator is movable with respect to the rack.

20. (Original) The device of claim 18 wherein the applicator comprises a plurality of nozzles.

21. (Currently Amended) The device of claim [[18]]20 wherein the plurality of nozzles has a first set of nozzles positioned above the rack and a second set of nozzles positioned below the rack.

22. (Previously Presented) The device of claim 18 wherein the control system controls the amount of liquid dispensed to the cleanroom material as a function of conductivity of the cleanroom material.

23. (Previously Presented) The device of claim 18 wherein the control system controls the amount of liquid dispensed to the cleanroom material as a function of mass of the cleanroom material.

24. (Previously Presented) The device of claim 18 wherein the control system controls the amount of liquid dispensed to the cleanroom material as a function of time.

25. (Currently Amended) The device of claim 18 further comprising a drainage and collection system for draining and collecting excess liquid ~~wherein the machine has a drainage and collection system~~.

26. (Previously Presented) A device for moistening a cleanroom material to a desired saturation level, the device comprising:

a chamber;

a rack positioned in the chamber for holding the cleanroom material;

an applicator for applying liquid to the cleanroom material;

a user interface for providing a user input signal;

a feedback system for providing a feedback signal which is a function of the saturation level of the cleanroom material; and

a control system for controlling the amount of liquid applied to the cleanroom material as a function of the user input signal and the feedback signal.

27. (Previously Presented) The device of claim 26 further comprising a pressure applicator for applying pressure to the cleanroom material to reduce liquid content of the cleanroom material.